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PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Docket No: Q64673

Teruji IKEMATSU

FAX RECEIVED

Appln. No.: 09/917,880✓

Group Art Unit: 2852

FEB 20 2003

Confirmation No.: 2071

Examiner: Michael P. Nghiem TECHNOLOGY CENTER 2800

Filed: July 31, 2001✓

For: METHOD FOR CONTROLLING EXPOSURE AND SCAN-EXPOSURE APPARATUS

AMENDMENT UNDER 37 C.F.R. § 1.111

Commissioner for Patents
Washington, D.C. 20231

Sir:

In response to the Office Action dated September 20, 2002, please amend the above-identified application as follows:

IN THE CLAIMS:

The claims are amended as follows:

1 (Amended). A method for controlling exposure, wherein a recording medium is irradiated with a light beam emitted from a light source which is moved along one of main scanning and sub-scanning directions by a light source scanning apparatus, the recording medium being moved along the other of the main scanning and the sub-scanning directions, to scan-expose the recording medium, the method comprising:

obtaining distance correction data which is generated by measuring distance between the recording medium and the light source while the light source is being moved by the light source scanning apparatus; and